

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Applicants: M. YAKUSHIJI, et al.
Serial No: 10/787,461
Filed: FEBRUARY 27, 2004
Title: PLASMA ETCHING APPARATUS AND PLASMA ETCHING METHOD
Group AU: 1763
Examiner: Luz L. Alejandro Mulero
Confirm. No: 7834

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

July 10, 2006

Sir:

In response to the Office Action mailed June 8, 2006, please amend the above-identified application as listed in the following, and as set forth on the following pages:

AMENDMENTS TO THE CLAIMS; and

REMARKS are included following the amendments.